



Pivotal Introduces the GFM-800 System—A Real Time In Situ Gas Flow Monitoring

GFM DELIVERS A CRITICAL REAL TIME VIEW INTO GAS FLOW DELIVERY SYSTEMS FOR CHAMBER MATCHING

Pleasanton, CA.—January 18, 2010—Pivotal Systems Corporation, the leader in advanced process monitoring and control solutions, today announced the launch of its GFM-800 product line. The GFM-800 provides a real time verification measurement of gas flow during wafer processing. The innovation lies in its ability to quickly and accurately calculate a rate of pressure drop measurement in a fixed volume within the gas stick as the MFC flows gas into the wafer processing chamber.

“As technology nodes continue to scale, gas flow control has become one of the biggest challenges in maintaining process consistency from chamber to chamber,” said Mukund Venkatesh, Pivotal’s Vice President of Marketing, “In the past, the only way to verify proper MFC operation was to take the chamber off-line and perform a rate of pressure rise measurement. Pivotal’s GFM-800 is a paradigm shift in gas flow calibration by measuring a rate of pressure drop in situ, during wafer processing. As a result, GFM measures gas flow for each and every gas, for each and every recipe step, of each and every production wafer, with no impact to throughput.” Venkatesh further pointed out that both IDM and OEM customers are very interested in the GFM-800 product line since they believe that real time gas flow delivery variations are a large and growing source of yield excursion and chamber matching issues.

“The GFM product line falls squarely within our vision to deliver wafer level monitoring and control solutions that enable significant gains in fab productivity for current and future technology nodes,” said John Hoffman, Pivotal’s Chief Executive Officer.

About Pivotal Systems

Pivotal Systems Corporation provides best-in-class monitoring and process control technology for the semiconductor manufacturing industry. Pivotal’s vision is to enable an order of magnitude increase in fab productivity and capital efficiency for current and future technology nodes. This vision is achieved through its real time in situ process monitoring and control solutions. Founded in 2003 and based in Pleasanton, California, the company is led by veterans from the semiconductor and high-tech industries. For more information about Pivotal, please visit www.pivotalsys.com, or send an email to info@pivotalsys.com.